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MEMS 2010 PROGRAM SCHEDULE

Sunday, 24 January 2010

15:00 – 18:00 *Registration*
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Monday, 25 January 2010

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08:30 – 08:50 *Opening Ceremony*

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B.J. Lin
TSMC, Ltd., TAIWAN

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¹ *University of Southern California, USA,*
² *University at Buffalo, The State University of New York, USA*

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K.F. Böhringer, *University of Washington, USA*

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C.-H. Lin, *National Sun Yat-Sen University, TAIWAN*

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ETH Zurich, SWITZERLAND

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¹ *Dublin City University, IRELAND*, ² *Universidad de Valparaíso, CHILE*

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National Cheng Kung University, TAIWAN

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L. Buchaillet, *Institute of Electronics, Microelectronics and Nanotechnology (IEMN), FRANCE*

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		¹ <i>Stanford University, USA</i> , ² <i>Indian Institute of Technology Delhi, INDIA</i>	
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		¹ <i>NanoLab, Ecole Polytechnique Fédérale de Lausanne, SWITZERLAND</i> , ² <i>CEA, IRAMIS, SPEC, Laboratoire d'Electronique Moléculaire, FRANCE</i> , ³ <i>LAAS CNRS, MINC (G37), FRANCE</i>	
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S. Tanaka, *Tohoku University, JAPAN*

O. Brand, *Georgia Institute of Technology, USA*

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E. Yeatman, *Imperial College, UK*

Y. Zohar, *University of Arizona, USA*

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¹ *Kyoto University, JAPAN*, ² *Panasonic Electric Works, Ltd., JAPAN*

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¹ *University of Pittsburgh, USA*, ² *Myongji University, KOREA*

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B. Dunn, C.-J. Kim, S. Tolbert
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R. Ghodssi, *University of Maryland, USA*

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Session Chairs:

H. Zappe, *University of Freiburg, GERMANY*

J.-B. Yoon, *Korea Advanced Institute of Science and Technology, KOREA*

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		² <i>Institute of Microelectronics, SINGAPORE,</i> ³ <i>ESIEE, FRANCE</i>	
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Session Chairs:

F. Ayazi, *Georgia Institute of Technology, USA*

T. Seki, *Omron Corporation, JAPAN*

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		¹ <i>CEA, Léti, MINATEC, FRANCE,</i> ² <i>Freescale Semiconductor, USA</i>	
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Session Chairs:

C.H. Hierold, *Swiss Federal Institute of Technology Zurich, SWITZERLAND*

E. Yoon, *University of Michigan, USA*

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		¹ <i>Nagoya Institute of Technology, JAPAN</i> , ² <i>University of Freiburg, GERMANY</i>	
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Thursday, 28 January 2010

07:30 – 12:00 **Registration**

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Session Chairs:

C.-J. Kim, *University of California, Los Angeles, USA*

S. Franssila, *Helsinki University of Technology, FINLAND*

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¹ *Ritsumeikan University, JAPAN*, ² *Murata Machinery, Ltd., JAPAN*
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¹ *PRESTO, JST, JAPAN*, ² *Tohoku University, JAPAN*

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Session Chairs:

U.-M. Gomez, *Robert Bosch GmbH, GERMANY*

C.-W. Baek, *Chung-Ang University, KOREA*

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¹ *Politecnico di Milano, ITALY*, ² *STMicroelectronics, ITALY*
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¹ *Korea Advanced Institute of Science and Technology, KOREA*,
² *Korea Research Institute of Standards and Science, KOREA*

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		M. Winter ^{1,2} , G. Feiertag ³ , C. Siegel ² , A. Leidl ² , H. Seidel ¹ ¹ Saarland University, GERMANY, ² EPCOS AG, GERMANY, ³ University of Applied Sciences-München, GERMANY	
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Session Chairs:

J. Brugger, *Ecole Polytechnique Fédérale de Lausanne, SWITZERLAND*

R. Baskaran, *Intel Components Research, USA*

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Session Chairs:

Y. Hanein, *University of Tel Aviv, ISRAEL*

X. Zhang, *Boston University, USA*

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